IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Takashi KOBAYASHI et al.

Appln. No.:

Filed: HEREWITH

For: NONVOLATILE SEMICONDUCTOR MEMORY DEVICE AND

METHOD OF MANUFACTURING THEREOF

\* \* \*

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

The documents on the attached List were cited in the specification, on pages 1, 3 and 23, and their relevance is indicated therein.

Respectfully submitted,

MWS:sjk

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Reg. No. 31,568

Mitchell

November 26, 2003

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